

### REMARKS/ARGUMENTS

The title, the specification, the abstract and drawings have been correspondingly amended without adding new matters and will be explained as 5 below.

In the title of the invention, a new title "**CLEANING SYSTEM HAVING A COMBINATION OF A SUBSTRATE AND A FRAME LAYER BEING CLEANED**" is given.

10 In the specification and abstract, the changes include the following features without adding new matters.

1. The "cleaning mechanism" is changed to the suitable "cleaning system".
2. Some grammar and usage errors are corrected.
3. The combination of the substrate and the frame layer of FIG. 4 is defined as an image sensor semi-package because the image sensor is not completely 15 packaged.
4. The periphery wall 58 is connected to the lower element 56, and the upped cover 60 is connected to the periphery wall 58 to form a cleaning room 62. This feature has been clearly shown in FIGS. 3 and 4.
5. The rotating device 52 is configured to fix the combination of the substrate 20 64 and the frame layer 66 with the chamber 68 facing the cleaning device 54. This feature has been clearly shown in FIG. 4.
6. The cleaner of the cleaning device 54 is ejected in a direction opposite to a direction of a centrifugal force of the combination of the substrate 64 and the frame layer 66. This feature has been clearly shown in the original drawings.

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Claims 1-5 are now present in this application. Claims 1-5 have been amended according to the amended specification and FIGS. 3 and 4.

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### Claim Objections

The examiner objects claim 1.

In response to the objection, claim 1 has been amended to overcome the objection.

**Claim rejections – 35 U.S.C. 112**

5 Claim 1 is rejected under 35 U.S.C. 112.

In response to the rejection, claim 1 has been amended to overcome the problem of the insufficient antecedent basis. Also, claim 1 has been amended to point out that the substrate is included in the claimed invention.

10 **Claim rejections – 35 U.S.C. 102**

The examiner rejects claims 1-5 under 35 U.S.C. 102(b) as being anticipated by Shih (US 2002/0036004).

Claim 1 has been amended to state that:

the cleaning system includes a combination of a substrate and a frame layer  
15 arranged on the substrate to form a chamber together with the substrate;

the cleaner is ejected from the cleaning device in a direction opposite to a direction of a centrifugal force of the combination of the substrate and the frame layer;

the cleaning device is for cleaning the chamber of the substrate by a cleaner  
20 ejected directly from the cleaning device into the chamber; and

the rotating device is configured to fix the combination of the substrate and the frame layer with the chamber facing the cleaning device.

Shih does not teach that:

the cleaning system includes a combination of a substrate and a frame layer  
25 arranged on the substrate to form a chamber together with the substrate;

the cleaning device is for cleaning the chamber of the substrate by a cleaner ejected directly from the cleaning device into the chamber; and

the rotating device is configured to fix the combination of the substrate and the frame layer with the chamber facing the cleaning device.

In fact, Shih's rotating device (substrate support) 120 may comprise a bracket 122 with radially extending arms 123, which cannot be used to fix the combination of the substrate and the frame layer of the invention with the chamber of the invention facing the cleaning device 130a or 130b. One of ordinary skill in the art may easily understand that the radially extending arms 123 only can fix the combination of the substrate and the frame layer of the invention with the chamber of the invention facing upward but not the cleaning device 130a or 130b.

Considerations of the amended claim 1 and its dependent claims 2-5 are therefore politely requested.

In light of the above-mentioned amendments and remarks, Applicant now asserts that all of the grounds for and objections and rejections have been traversed or overcome by amendments, and that all of the present claims are in condition for immediate allowance. Applicant therefore requests reconsideration of the rejections and objections, and solicits allowance of the present claims at an early date.

Thank you for your consideration.

Respectfully submitted,

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Date: Joe Liu 02/14/2007

Joe Liu

Title of Officer: President of Kingpak Technology Inc.,  
the Assignee of this application

Address: No. 84, Taiho Road, Chupei, Hsinchu Hsien, Taiwan

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